



Traceability North America TC Chapter Meeting Summary and Minutes

NA Fall Meetings

Thursday, November 10, 2022

4:00-7:00 PM Pacific Time

SEMI HQ, Milpitas

TC Chapter Announcements

Next TC Chapter Meeting

Wednesday, April 5, 2023

4:00-7:00 PM Pacific Time

SEMI HQ, Milpitas

Table 1 Meeting Attendees

Italics indicate virtual participants

Co-Chairs: Yaw Obeng (NIST), Dave Huntley (PDF Solutions)

SEMI Staff: Michelle Sun

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Applied Materials, Inc.	Khedkar	Jaydeep	Samsung	<i>Bruce</i>	<i>Eric</i>
GLOBALFOUNDRIES	<i>Hanan</i>	<i>Jeff</i>	SCREEN Semiconductor Solution Co., Ltd.	<i>Nishimura</i>	<i>Takayuki</i>
Hitachi High-Tech Corporation	<i>Toyoshima</i>	<i>Yuko</i>	SEMI	Sun	Michelle
Hitachi High-Tech Corporation	<i>Tomizawa</i>	<i>Yuki</i>	SEMI	Trio	Paul
Lam Research Corporation	<i>Arrendondo</i>	<i>Manuel</i>	Sony Group Corporation	<i>Hanakura</i>	<i>Yuuri</i>
Lam Research Corporation	Celli	David	Tokyo Electron Limited	Machida	Ryo
Multibeam Corporation	<i>Prescop</i>	<i>Ted</i>	Tokyo Electron Limited	<i>Akimoto</i>	<i>Toshikazu</i>
NIST - National Institute of Standards & Technology	<i>Obeng</i>	Yaw	Tokyo Electron Ltd.	Mashiro	Supika
PEER Group Inc.	<i>Fuchigami</i>	<i>Albert</i>	Wolfsped, Inc.	<i>Barbieri</i>	<i>Tom</i>
X-FAB Sarawak Sdn. Bhd	<i>Liew</i>	<i>Emily</i>			

Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
None		

Table 3 Committee Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
None	

**Table 4 Ballot Results**

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
6698C	Specification for Serial Alphanumeric Marking of the Front Surface of Wafers, with title change to: SPECIFICATION FOR SERIAL ALPHANUMERIC MARKING OF THE FRONT SURFACE OF SILICON WAFERS	Passed

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Activities Approved by the GCS between meetings of the TC Chapter

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None			

Table 6 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None			

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

Table 7 Authorized Ballots

<i>#</i>	<i>When</i>	<i>TF</i>	<i>Details</i>
None			

Table 8 SNARF(s) Granted a One-Year Extension

<i>#</i>	<i>TF</i>	<i>Title</i>	<i>Expiration Date</i>
6504	SDT	New Standard: Specification for Counterfeit Prevention for the Electronics Manufacturing Supply Chain	11/10/2023
6449	EMT	New Standard: Specification for Equipment and Materials Part Traceability	11/10/2023

Table 9 SNARF(s) Abolished

<i>#</i>	<i>TF</i>	<i>Title</i>
6448	EMT	New Standard: Specification for Material and Part Labels

Table 10 Standard(s) to receive Inactive Status

<i>Standard Designation</i>	<i>Title</i>
None	

Table 11 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
None		

Table 12 Previous Meeting Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
None		

1 Welcome, Reminders, and Introductions

Yaw Obeng (NIST) called the meeting to order at 4:09. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: Required Meeting Elements Nov 2022

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion: Approve the minutes as written

By / 2nd: Albert Fuchigami (PEER Group Inc.) / David Celli (Lam Research)

Discussion: None

Vote: 12-Y 0-N. Motion passed.

Attachment: Trace-Minutes-Apr-2022

3 Liaison Reports

3.1 Traceability Japan TC Chapter

Michelle Sun (SEMI) reported for the Traceability Japan TC Chapter. Of note:

- Meeting Information
 - Last Meeting: June 16, 2022, at SEMI Japan Office
 - Next Meeting: December 14, 2022, at SEMICON Japan
- Ballot Results
 - 6674A: New Standard: Specification for ID Marking for Glass Carrier Characteristics of Panel Level Packaging (PLP) Applications **[Passed with editorial changes]**

Attachment: JA_Trace_Liaison_20220616_v1

3.2 SEMI Staff Report

Michelle Sun (SEMI) gave the SEMI Staff Report. Of note:

SEMI Global 2022 & 2023 Calendar of Events

- SEMICON Europa
 - Nov 15-18
 - Munich, Germany
- SEMICON Japan
 - Dec 14-16
 - Tokyo, Japan
- SEMICON Korea
 - Feb 1-3, 2023
 - Seoul, Korea



- SEMICON China
 - o Mar 22-24, 2023
 - o Shanghai, China

NA Standards Spring Meetings

- April 3-6, 2023
- SEMI HQ, Milpitas, California/US

Critical Dates for SEMI Standards Ballots

2022	Ballot Submission Deadline	Voting Opens	Voting Closes
Cycle 8	October 4	October 18	November 17
Cycle 9	November 15	November 29	December 29

2023	Ballot Submission Deadline	Voting Opens	Voting Closes
Cycle 1	January 4	January 18	February 17
Cycle 2	February 1	February 15	March 17
Cycle 3	March 8	March 22	April 21
Cycle 4	April 19	May 3	June 2

SEMI Standards Publications

- Total SEMI Standards in portfolio: 1,069
- Includes 320 Inactive Standards
- New Standards

Cycle	Designation	Title	Committee	Region
September 2022	SEMI F120	Test Method for the Electrochemical Critical Pitting Voltage Testing of Stainless Steel Used in Corrosive Gas Systems	Gases	NA
September 2022	SEMI E120.2	Specification for Protocol Buffers for Common Equipment Model (CEM)	Information & Control	NA
October 2022	SEMI E125.2	Specification for Protocol Buffers for Equipment Self Description (EqSD)	Information & Control	NA
October 2022	SEMI E134.2	Specification for Protocol Buffers of Data Collection Management	Information & Control	NA
October 2022	SEMI E142.4	Specification for SECS II Protocol for Substrate Mapping Using Item Transfer	Information & Control	NA

Publications Backlog

Processing Queue: 37	YTD Published: 93
5/5/2022 A&R cycle: 8 6/30/2022 A&R cycle: 11 8/18/2022 A&R cycle: 9	New Standards: 11 Revisions: 43 Reapprovals: 36

Contributing Factors

- Increased A&R cycles have resulted in a constant rate of documents for processing.
- Ballots are becoming more complex and require more time to process.
- As the Regulations, Procedure Manual, and Style Manual are updated, there is the potential for delays in processing documents (e.g., ensuring documents comply).

SNARF 3-Year Status

- 6504, New Standard: Specification for Counterfeit Prevention for the Electronics Manufacturing Supply Chain (Extend)
- 6448, New Standard: Specification for Material and Part Labels
- 6449, New Standard: Specification for Equipment and Materials Part Traceability

Attachment: Staff Report Nov 2022 v6 - Trace

4 Ballot Review

NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

4.1 Document #6698C, Specification for Serial Alphanumeric Marking of the Front Surface of Wafers, with title change to: SPECIFICATION FOR SERIAL ALPHANUMERIC MARKING OF THE FRONT SURFACE OF SILICON WAFERS

Motion: This is not a Safety Document, when all safety-related information is removed, the Document is still technically sound and complete. (Regulations ¶ 8.7.1)

By / 2nd: David Celli (Lam Research) / Jaydeep Khedkar (AMAT)

Discussion: None

Vote: 11-Y 0-N. Motion passed.

Motion: This Document passed TC Chapter review as balloted and will be forwarded to the ISC A&R SC for procedural review.

By / 2nd: David Celli (Lam Research) / Jaydeep Khedkar (AMAT)

Discussion: None

Vote: 10-Y 0-N. Motion passed.

Attachment: AR Form - 6698C

4.2 PCR for SEMI M12-0706 (Reapproved 0318), Specification for Serial Alphanumeric Marking of the Front Surface of Wafers

Motion: To approve editorial change(s).

By / 2nd: David Celli (Lam Research) / Jaydeep Khedkar (AMAT)

Discussion: None

Vote: 8-Y 0-N. Motion passed.



Motion: This is not a Safety Document, when all safety-related information is removed, the Document is still technically sound and complete. (Regulations ¶ 8.7.1)

By / 2nd: David Celli (Lam Research) / Jaydeep Khedkar (AMAT)

Discussion: None

Vote: 10-Y 0-N. Motion passed.

Motion: This Document passed TC Chapter review as balloted and will be forwarded to the ISC A&R SC for procedural review.

By / 2nd: David Celli (Lam Research) / Jaydeep Khedkar (AMAT)

Discussion: None

Vote: 9-Y 0-N. Motion passed.

Attachment: PCR – M12

5 Subcommittee and Task Force Reports

5.1 Equipment and Materials Traceability Task Force

Motion: Abandon SNARF Document #6448

By / 2nd: Albert Fuchigami (PEER Group Inc.) / Supika Mashiro (Tokyo Electron Ltd.)

Discussion: Development is moving towards primary-subordinate approach. Document 6448 is not the current favored approach, therefore the task force is looking to abolish it. A future SNARF for the primary standard will be submitted.

Vote: 8-Y 0-N. Motion passed.

Motion: Approve a 1 year extension of the project period for the SNARF Document #6449

By / 2nd: Albert Fuchigami (PEER Group Inc.) / Supika Mashiro (Tokyo Electron Ltd.)

Discussion: None

Vote: 11-Y 0-N. Motion passed.

5.2 Single Device Traceability Task Force

Motion: Approve a 1 year extension of the project period for the SNARF Document #6504

By / 2nd: David Celli (Lam Research Corporation) / Jaydeep Khedkar (Applied Materials, Inc.)

Discussion: None

Vote: 6-Y 0-N. Motion passed.

6 Next Meeting and Adjournment

The next meeting is scheduled for Wednesday, April 5, 2023 from 4:00-7:00 PM Pacific Time at Milpitas, CA. See <http://www.semi.org/standards-events> for the current list of events.

Adjournment: 7:03.

Respectfully submitted by:

Michelle Sun



Coordinator, International Standards
SEMI Global Headquarters
Phone: +1.408.943.7982
Email: msun@semi.org

Minutes tentatively approved by:

Dave Huntley (PDF Solutions), Co-chair	1/4/2023
Yaw Obeng (NIST), Co-chair	1/5/2023

Table 13 Index of Available Attachments^{#1}

<i>Title</i>	<i>Title</i>
Required Meeting Elements Nov 2022	Trace-Minutes-Apr-2022
JA_Trace_Liaison_20220616_v1	Staff Report Nov 2022 v6 - Trace
6698C_Ballot Review	PCR - M12

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.